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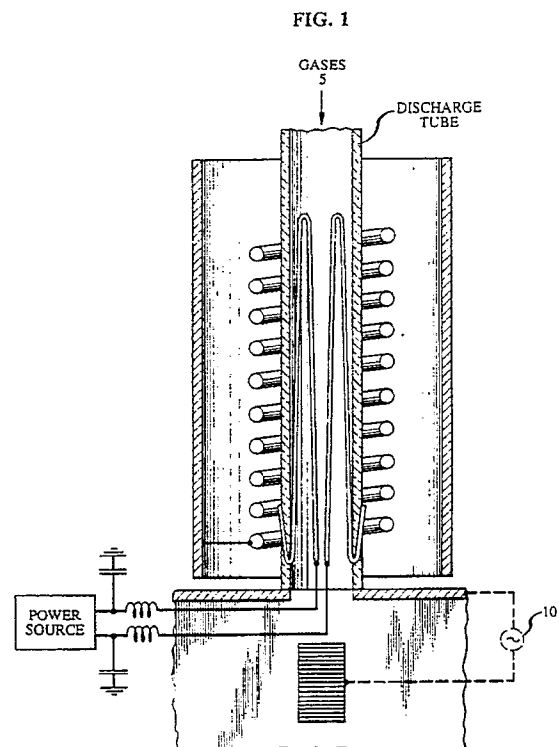
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54 Processes depending on plasma generation.

57 Anisotropic plasma etching is accomplished utilizing a helical resonator operated at relatively low gas pressure. The use of this combination yields an extremely high flux of ionic species with resulting rapid anisotropic etching. A helical resonator in conjunction with suitable precursors is also quite useful for plasma induced deposition.



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DOCUMENTS CONSIDERED TO BE RELEVANT			
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int. Cl.5)
X,Y,A	US-A-4 233 109 (J NISHIZAWA) * column 5, last paragraph; figure 3 ** column 7, line 40 - column 8, line 14; figures 5A-5C ** column 4, last paragraph; claims 5, 19 *	1,2,12,14, 15,24,4,5, 17,18,39	H 01 J 37/32 H 05 H 1/18
Y,A	IBM TECHNICAL DISCLOSURE BULLETIN. vol. 28, no. 4, September 1985, NEW YORK US pages 1694 - 1696; "R F MODULATION DEVICE AND TECHNIQUE FOR PLASMA PROCESSING AND DIAGNOSTICS" * page 1; figures 1, 3, 4 *	4,5,17,18, 26,27	
X	FR-A-1 442 502 (INTERNATIONAL STANDARD ELECTRIC CORPORATION) * page 2; figure 1 *	25	
A	EP-A-0 271 341 (C D DOBSON) * column 3-4; figure 2 *	25,30,35	
A	US-A-4 368 092 (G N STEINBERG) * column 3, lines 26 - 44; figure *	10,11,22, 23,31,39	
A	US-A-3 297 465 (R A CONNELL ET AL) * column 3; figure 2 *	3,16	TECHNICAL FIELDS SEARCHED (Int. Cl.5)
A	GB-A-1 299 803 (HUMPHREYS CORPORATION) * page 1, last paragraph - page 3, paragraph 1; figures 2, 4 *	13,29,36	H 01 J 37/00 H 05 H 1/00
A	PATENT ABSTRACTS OF JAPAN vol. 11, no. 63 (C-406)(2510) 26 February 1987, & JP-A-61 222534 (ANELVA CORP.) 03 October 1986, * the whole document *	37	
The present search report has been drawn up for all claims			
Place of search The Hague		Date of completion of search 22 April 91	Examiner HULNE S.L.
CATEGORY OF CITED DOCUMENTS X: particularly relevant if taken alone Y: particularly relevant if combined with another document of the same category A: technological background O: non-written disclosure P: intermediate document T: theory or principle underlying the invention		E: earlier patent document, but published on, or after the filing date D: document cited in the application L: document cited for other reasons &: member of the same patent family, corresponding document	